



Sheet 1 of 2

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)			ATTY. DOCKET NO. LBP-PT033		SERIAL NO. 10/766,463		
			APPLICANT Rembe et al.				
			FILING DATE January 28, 2004		GROUP 2877		
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>lje</i>	AA	6,084,672	07/04/00	Andrew Lewin	/	/	
<i>lje</i>	AB	6,404,545	06/11/02	Hiroshi Ishiwata	/	/	
<i>lje</i>	AC	6,181,431	01/30/01	Bernard Siu	/	/	
<i>lje</i>	AD	US 2002/089740	07/11/02	Jeffrey A. Beckstead Wetzel et al.	/	/	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES
<i>lje</i>	AE	JP 61-013233	01/86	Japan - Abstract	/	-	
<i>lje</i>	AF	WO 00/33727	06/00	PCT	/	/	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>lje</i>	AG	Q. S. Davis et al., "Using a Light Microscope to Measure Motions with Nanometer Accuracy", Optical Engineering, Vol. 37, 1998, pp. 1299-1304					
<i>lje</i>	AH	N. F. Smith et al., "Non-Destructive Resonant Frequency Measurements on MEMS Actuators", Proc. of IEEE CH37167, 39th Annual Internat'l Reliability Physics Symposium, Orlando, FL 2001, pp. 99-105					
<i>lje</i>	AI	Microscope Scanning Vibrometer MSV 300, Polytec Hardware Manual for Scanner Controller MSV-Z-040, Microscope Adapter OFV-074 and Scanner Unit OFV-073, Polytec GmbH, Waldbronn, Germany 2002					

<i>Paul J. Charles</i>	EXAMINER	DATE CONSIDERED
		9/22/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MP&P 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.